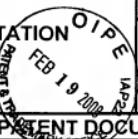


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<b>INFORMATION DISCLOSURE CITATION in an Application</b> (Use several sheets if necessary)							
Applicant Paul John Kawula							
Filing Date July 21, 2003		Group Art Unit 3738					
<b>U.S. PATENT DOCUMENTS</b>							
Examiner Initial	Ref. No.	Document Number	Date of Patent	Name	Class	Subclass	Filing Date if Appropriate
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Examiner Initial	Ref. No.	Document Number	Date of Patent	Name	Class	Subclass	Filing Date if Appropriate
		A2					
<b>FOREIGN PATENT DOCUMENTS</b>							
Examiner Initial	Ref. No.	Document Number	Date of Publication	Country	Class	Subclass	Translation Yes <input type="checkbox"/> No <input type="checkbox"/>
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